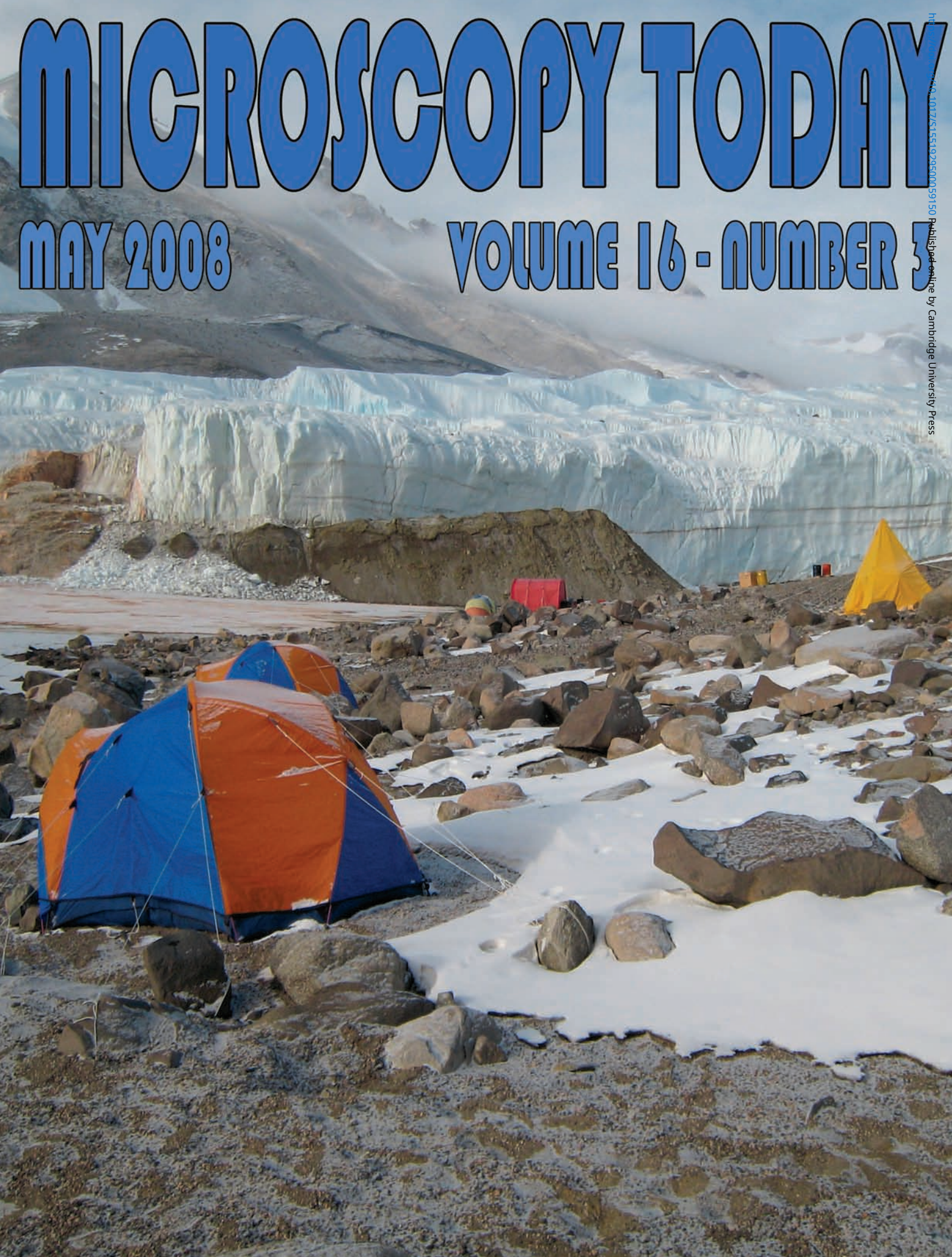


# MICROSCOPY TODAY

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# America's Next Top Model

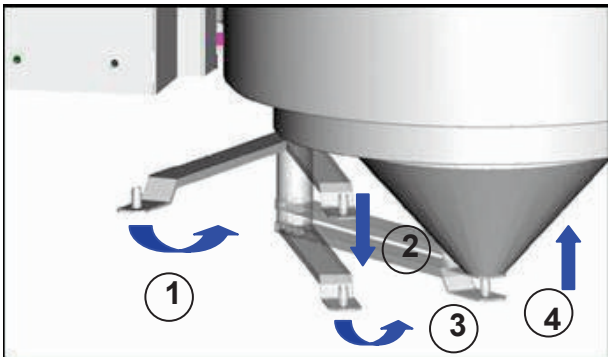
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Automated Differential Aperture (detail)



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